

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Peter CHOI

Title: PLASMA SOURCE OF DIRECTED BEAMS AND
APPLICATION THEREOF TO
MICROLITHOGRAPHY

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FIRST INFORMATION DISCLOSURE STATEMENT

Mail Stop PCT
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

In accordance with Rule 1.56 and MPEP Section 2001.06(a), the References listed on Form PTO-1449, were cited in the International Search Report for corresponding International Application PCT/FR2004/002656 and are hereby brought to the attention of the Examiner as being possibly material to examination of the subject patent application. An English language version of the International

Based Upon: PCT/FR2004/002656

Search Report, Form PCT/ISA/210 (4 pages), is also enclosed.

Form PTO-1449 (1 page) is enclosed with a copy of each and every Non-U.S. patent reference cited on Form PTO-1449.

Respectfully submitted,



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